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RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITING PROCEDURE
EXAMINING GROUP 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Su, *et al.* Docket No.: TSM03-0150
Serial No.: 10/675,862 Art Unit: 2823
Filed: September 30, 2003 Examiner: Fernando L. Toledo
For: Apparatus And Method For Manufacturing A Semiconductor Wafer With
Reduced Delamination And Peeling

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE UNDER 37 C.F.R. § 1.116

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H/1 6/16/06*

Dear Sir:

The following amendments and remarks are presented in response to the Examiner's
Final Office Action mailed April 4, 2006. Please amend the above-referenced application as
follows.